

1/9

FIG. 1

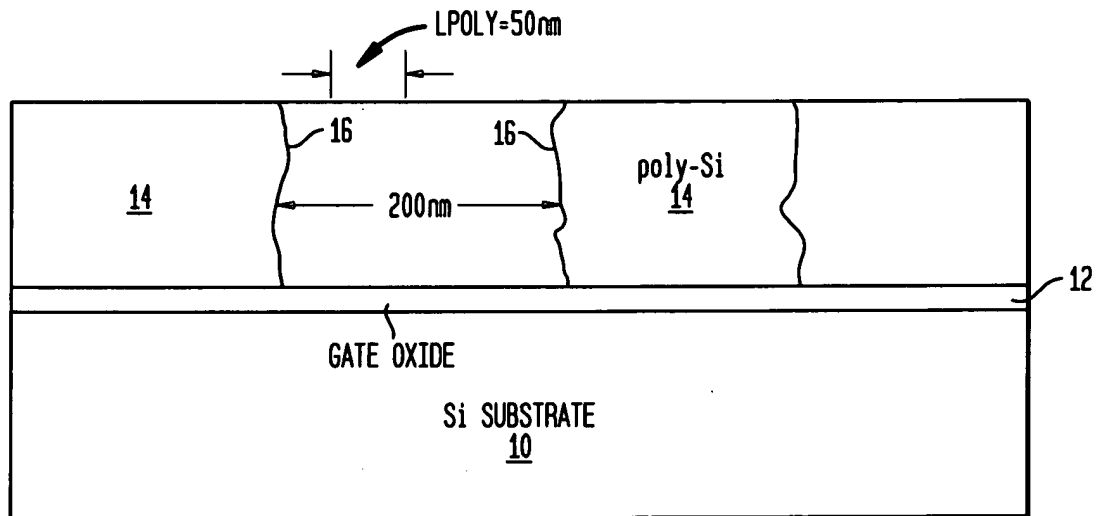


FIG. 2

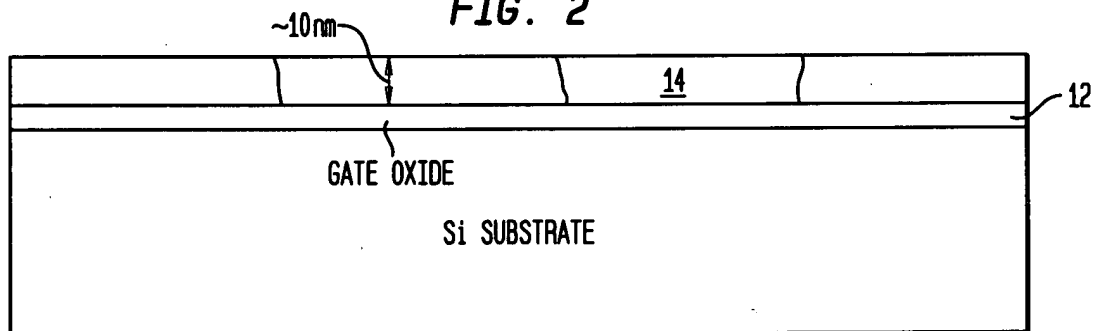


FIG. 3

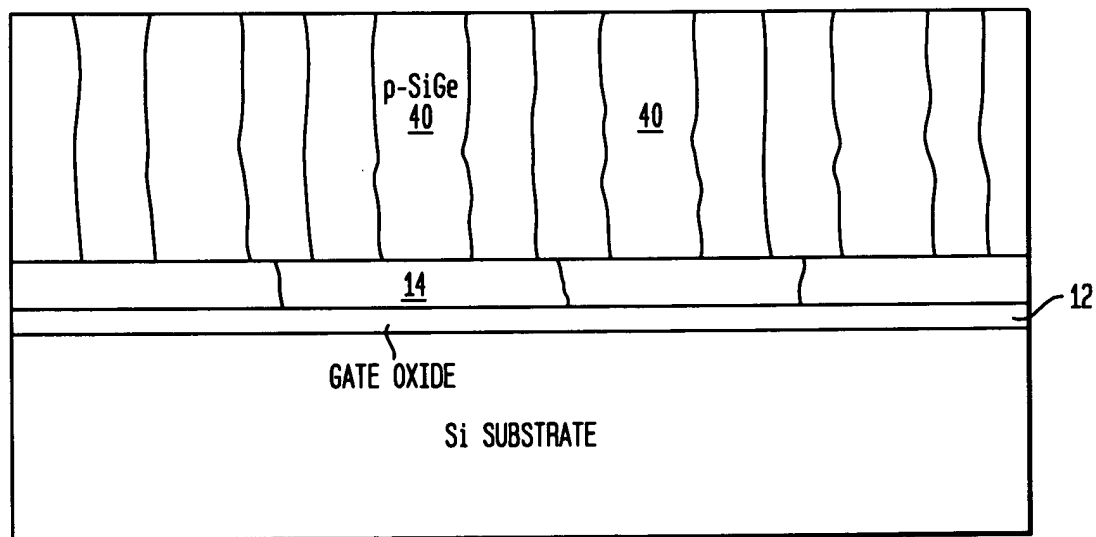
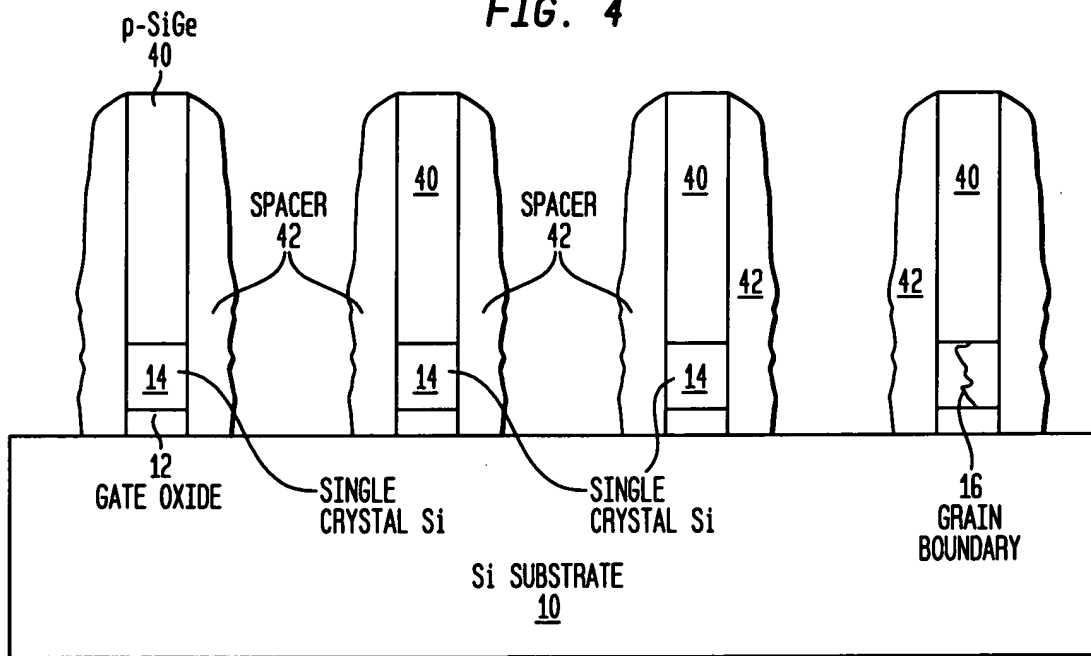
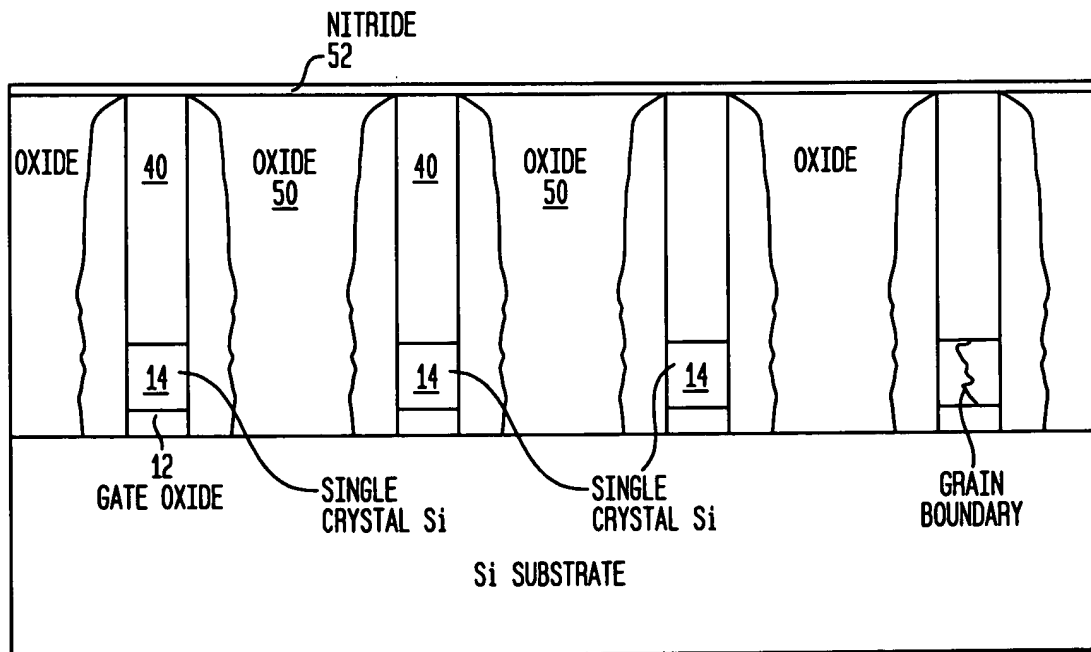


FIG. 4**FIG. 5**

3/9

FIG. 6

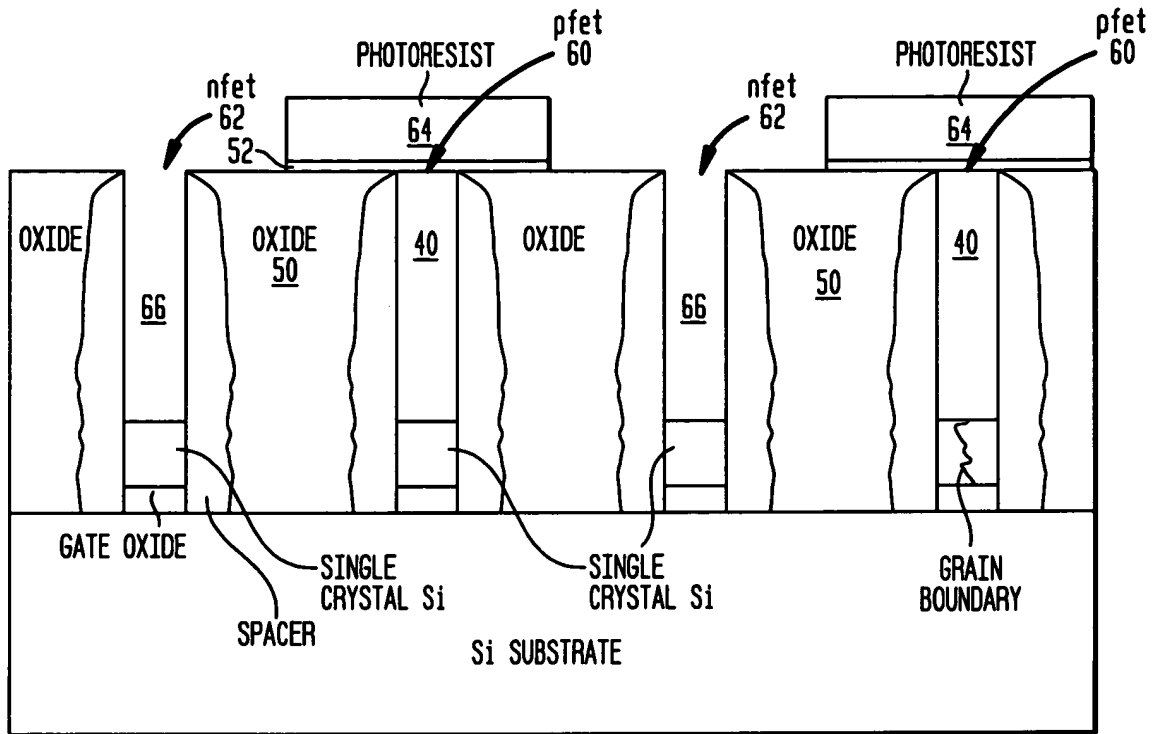
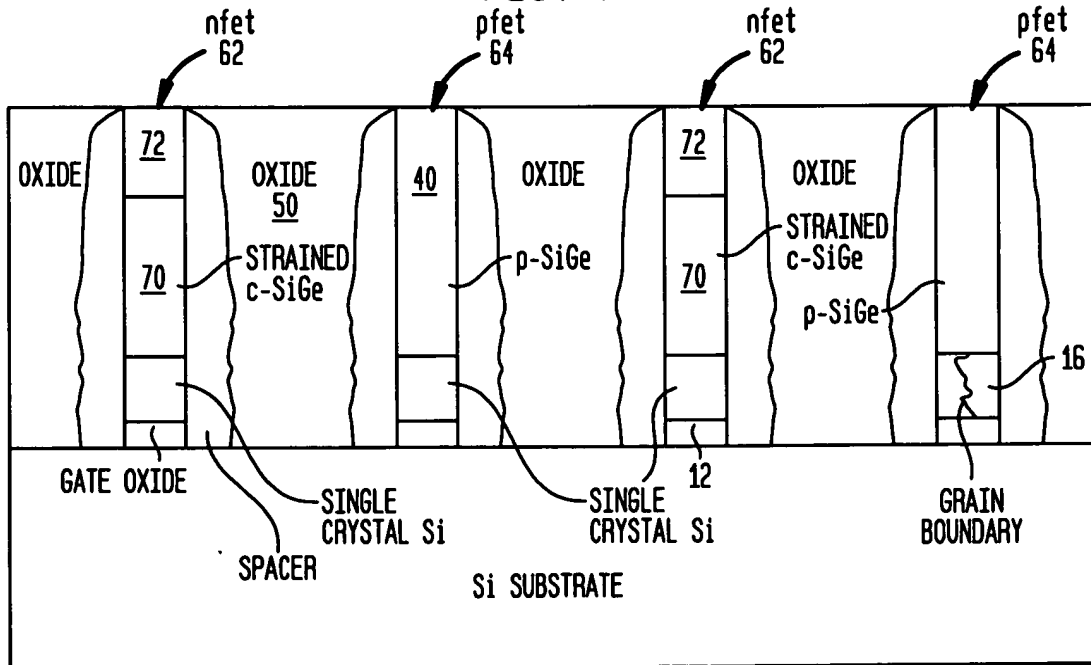
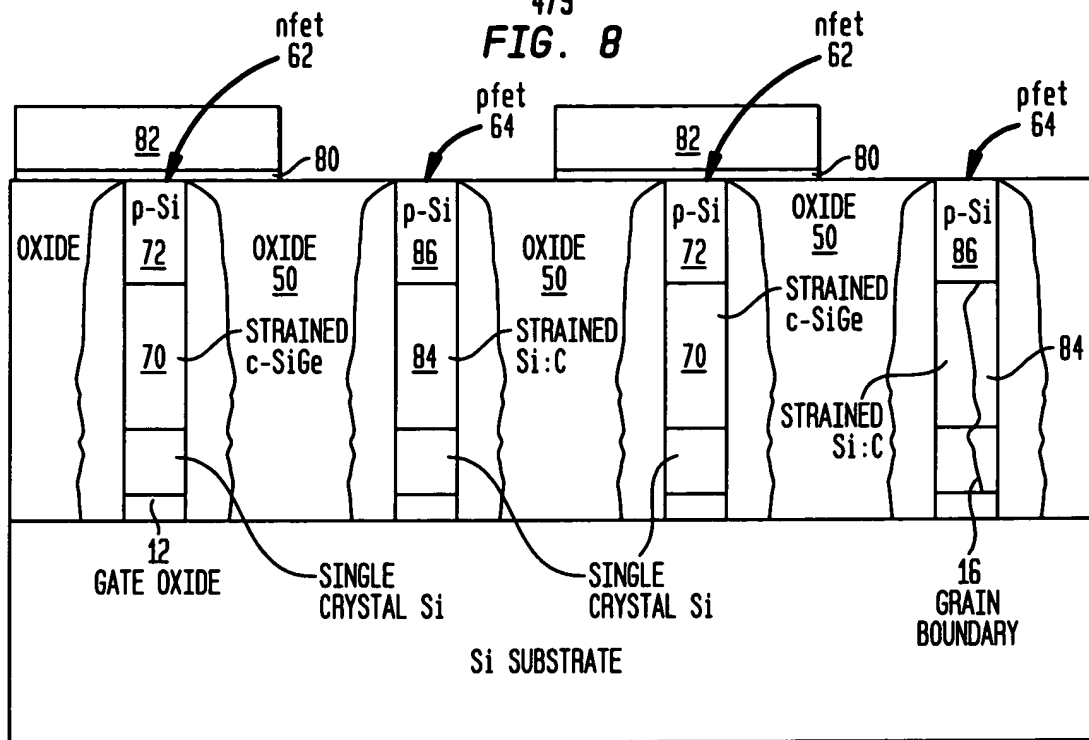
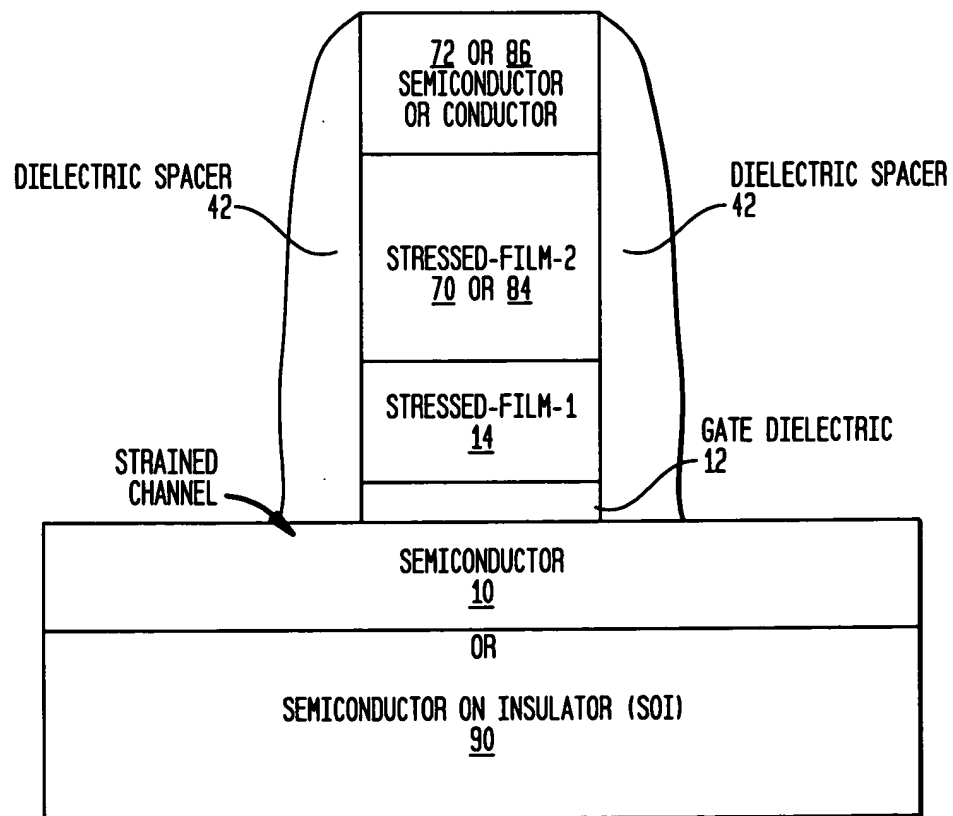


FIG. 7



4/9
FIG. 8**FIG. 9**

5/9

FIG. 10

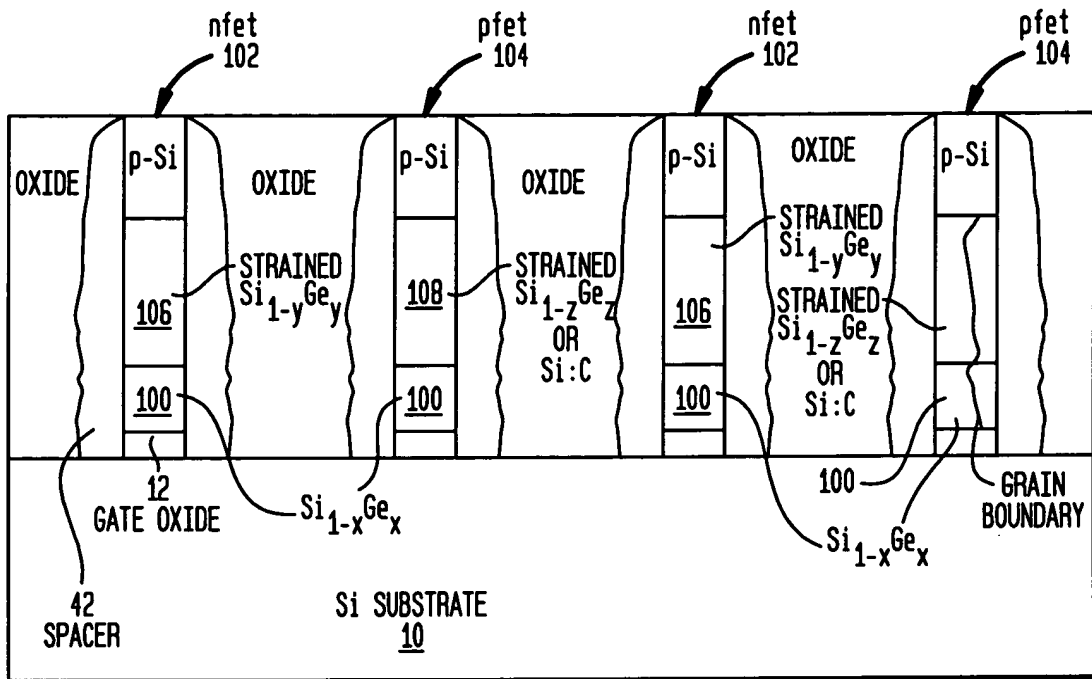
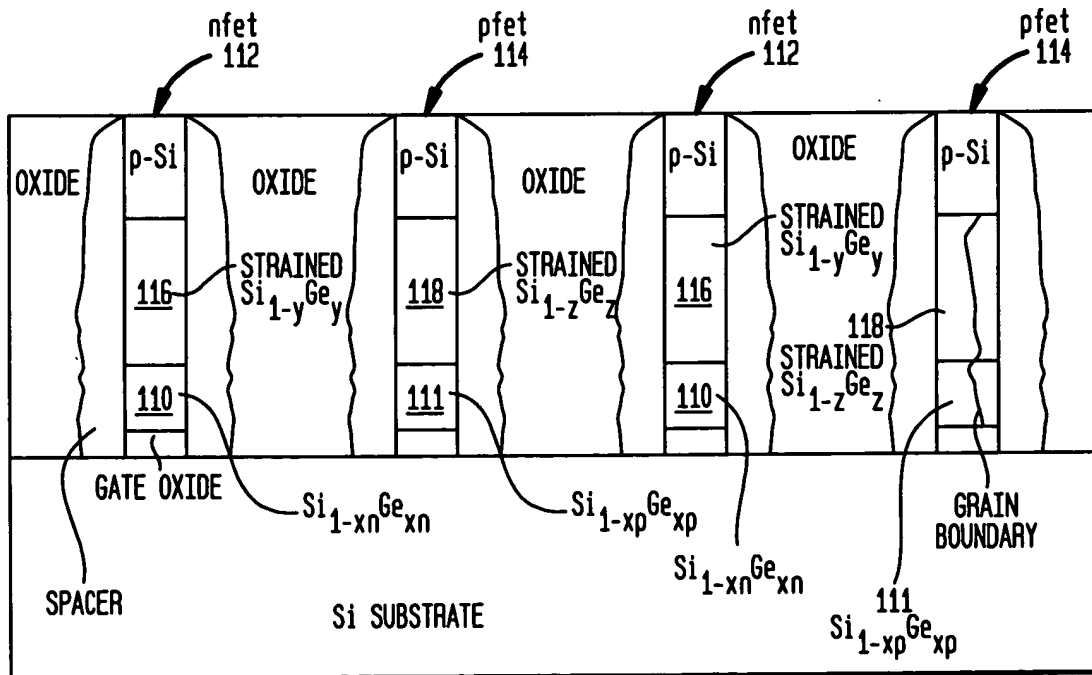


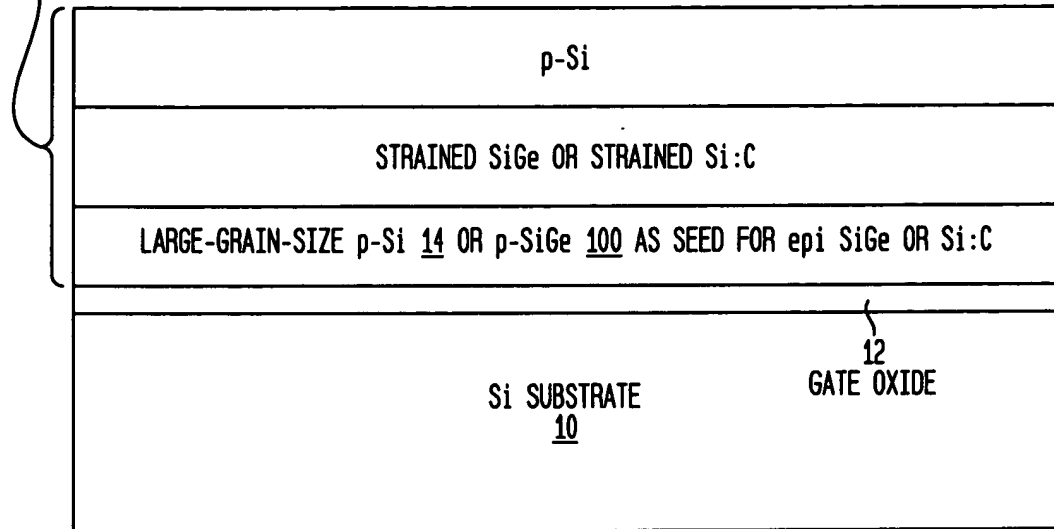
FIG. 11



6/9

FIG. 12GATE
STACKED-LAYER
120

SCHEMATIC OF LAYER STRUCTURE BEFORE GATE PATTERNING

**FIG. 13**

BONDED OXIDE/Si INTERFACE

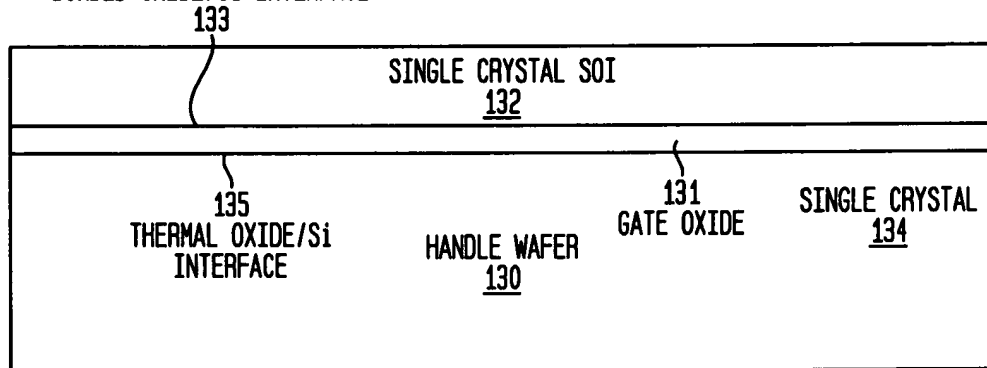
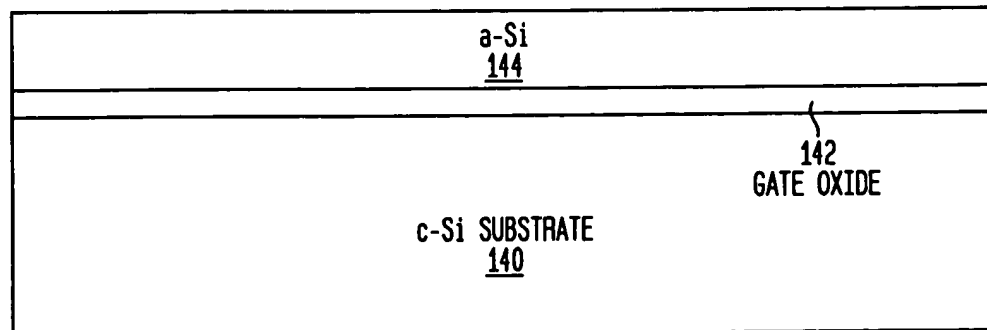
**FIG. 14**

FIG. 15

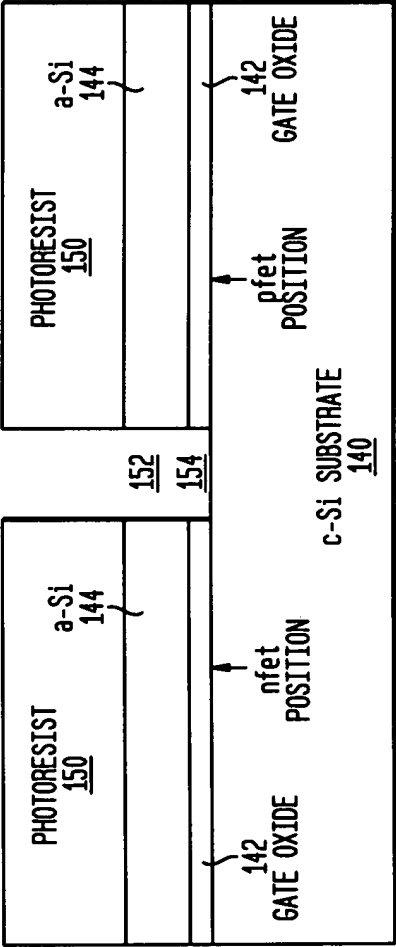


FIG. 16

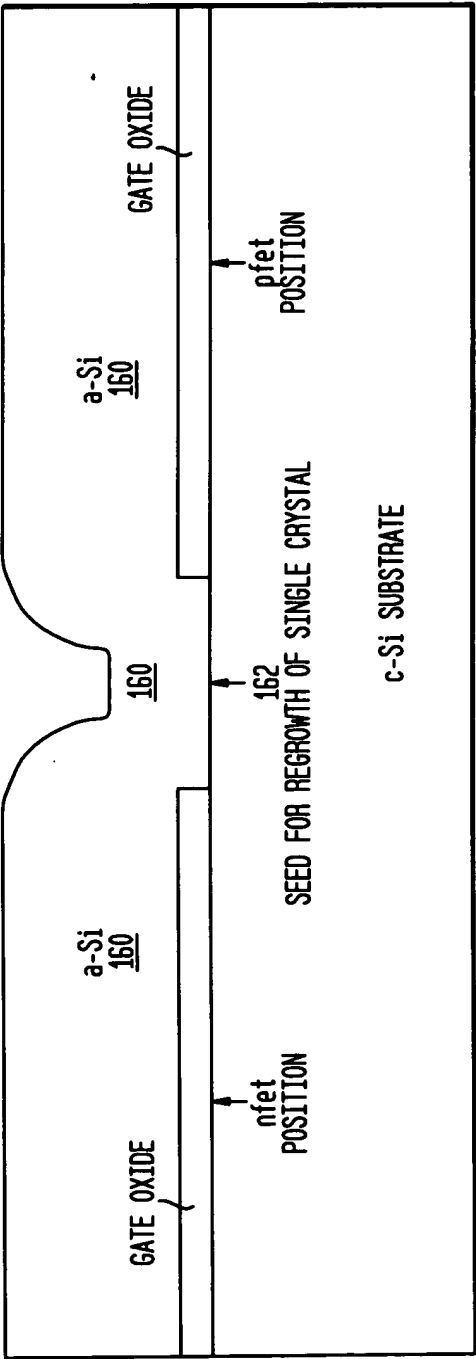


FIG. 17

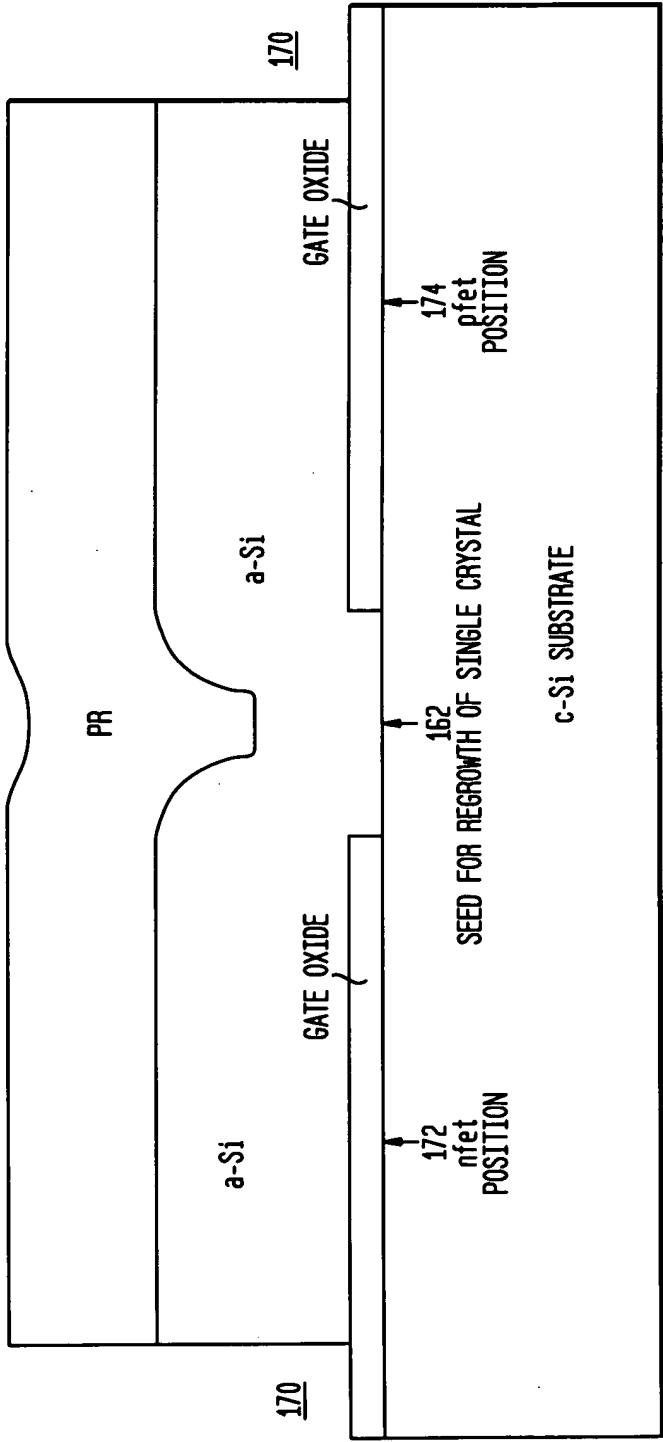


FIG. 18

